

Licensing Incentive Framework for Technologies (“LIFT”): Past Use

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过往专利使用部分

理论上的过往专利使用债务 (“PUTL”)
根据预设的专利许可费率来确定被许可人 理论上的
过往专利使用债务金额

Past Use Theoretical Liability (“PUTL”)

Determination of new licensee Past Use Theoretical
Liability based on the assumed royalty rate

Licensing Incentive Framework for Technologies (“LIFT”): Past Use

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Past Use Theoretical Liability (“PUTL”)
Determination of new licensee Past Use Theoretical
Liability based on the assumed royalty rate

系数“W”用于确定 “过往
专利使用应付金额”
 (“PULP”)

A liability coefficient “W” is
used to determine the Past Use
Liability Payable (“PULP”)

可许可市场的渗透率

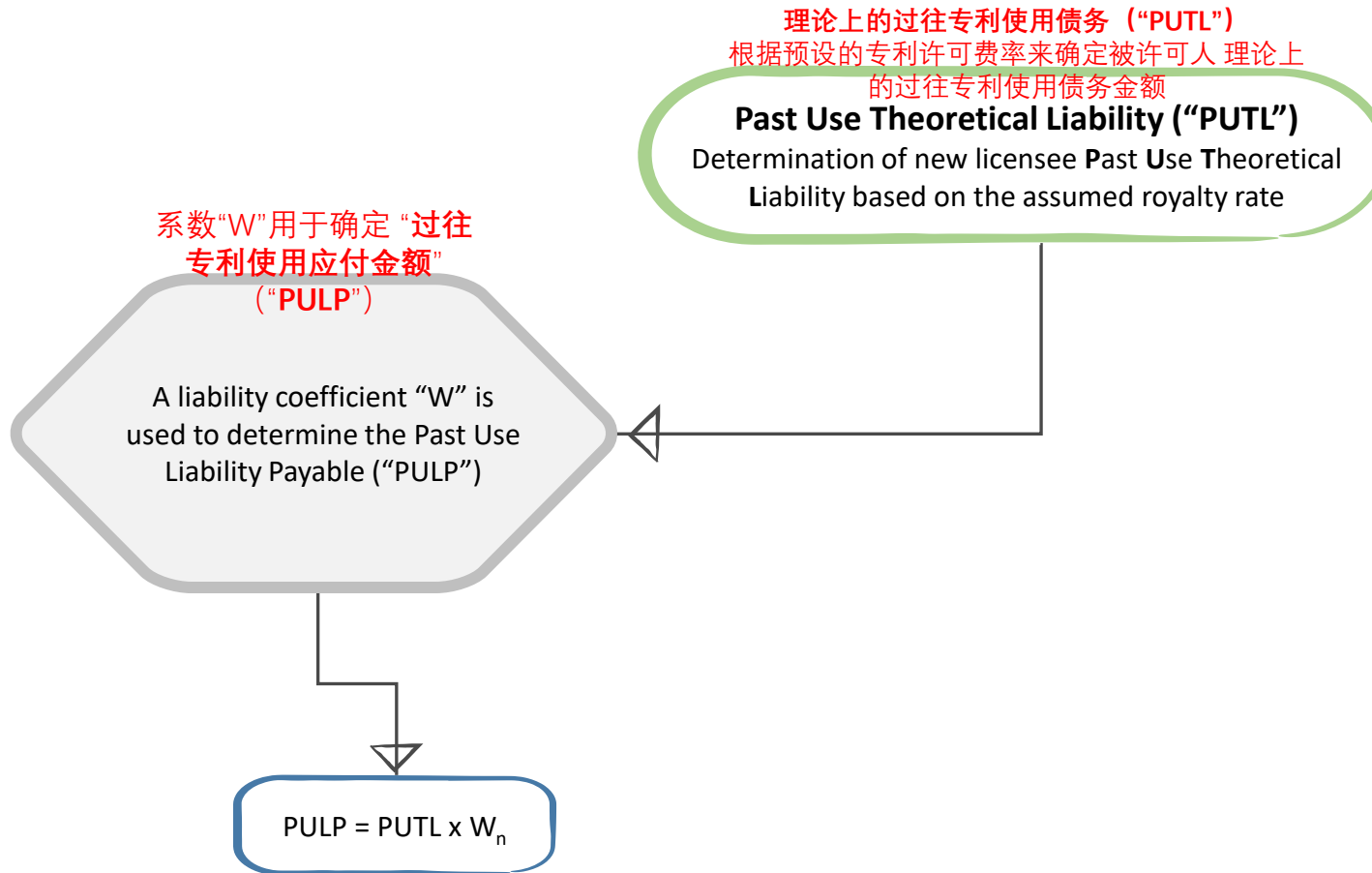
系数“W”

Licensable Market Penetration (“LMP”)	Coefficient W (“W”)
0% ≤ LMP < 5%	10%
5% ≤ LMP < 15%	15%
15% ≤ LMP < 25%	30%
25% ≤ LMP < 35%	45%
35% ≤ LMP < 45%	60%
45% ≤ LMP < 55%	80%
55% ≤ LMP	100%

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过往专利使用部分

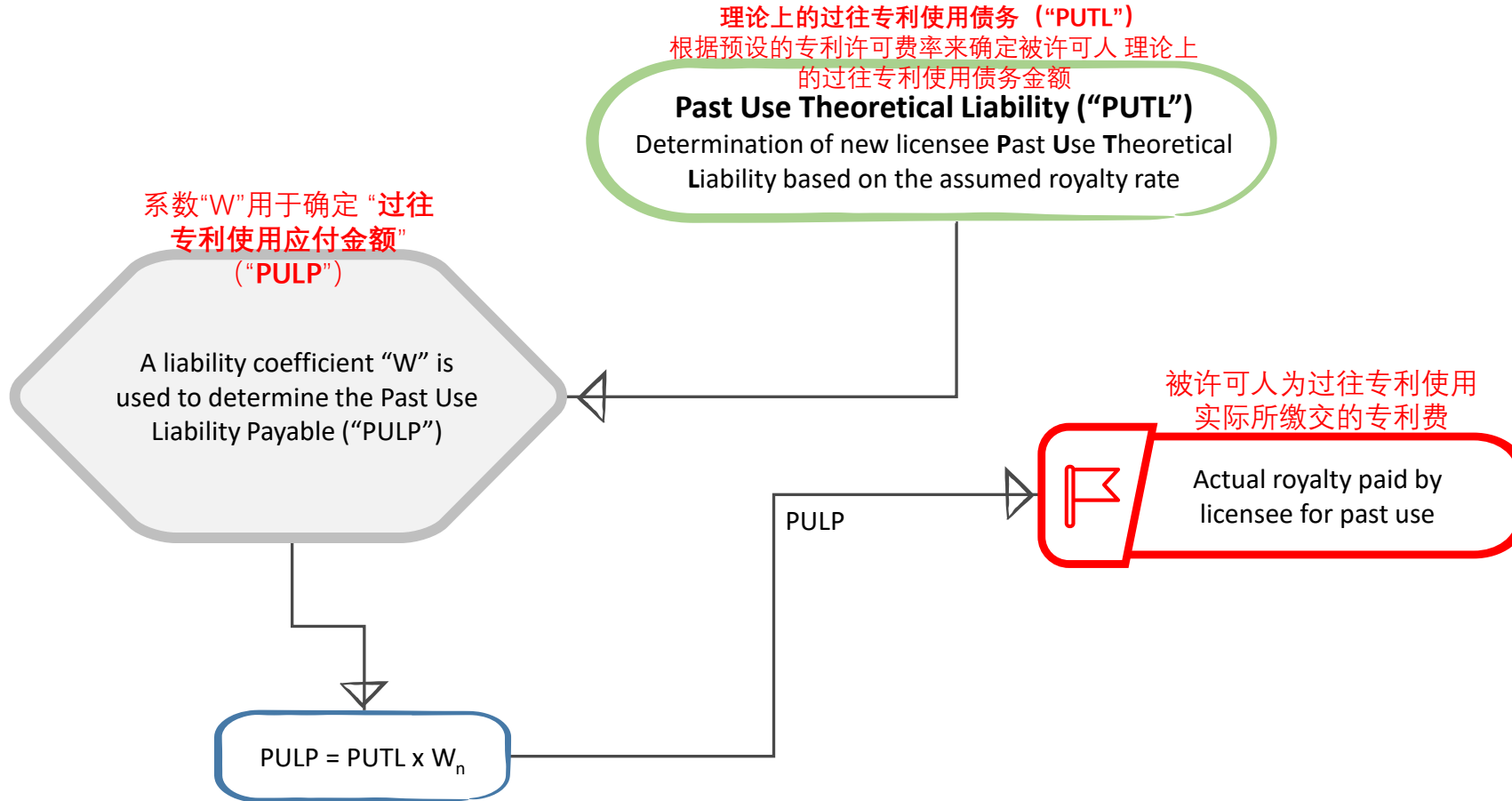


过往专利使用部分

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过往专利使用部分

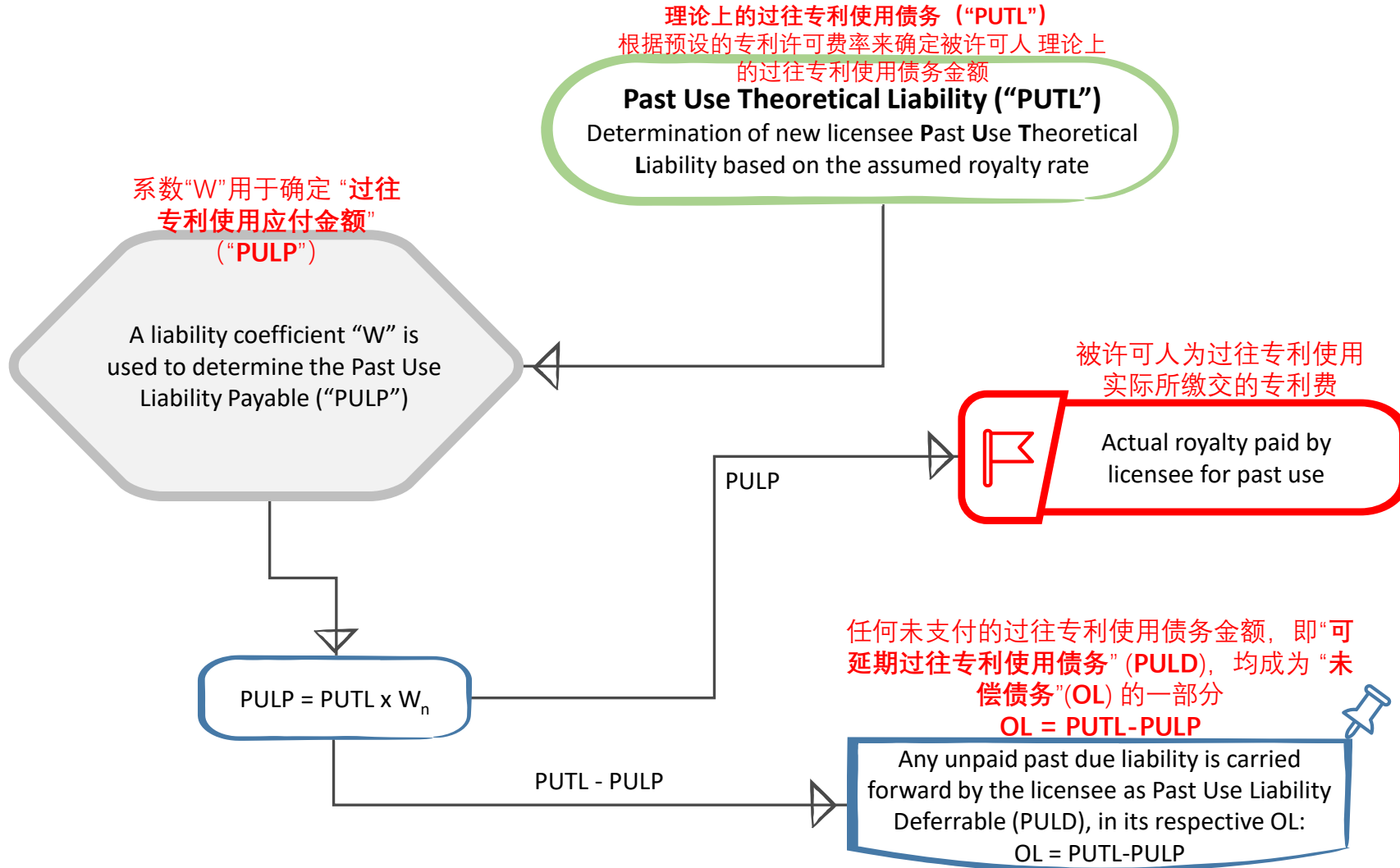


过往专利使用部分

Licensing Incentive Framework for Technologies (“LIFT”): Past Use

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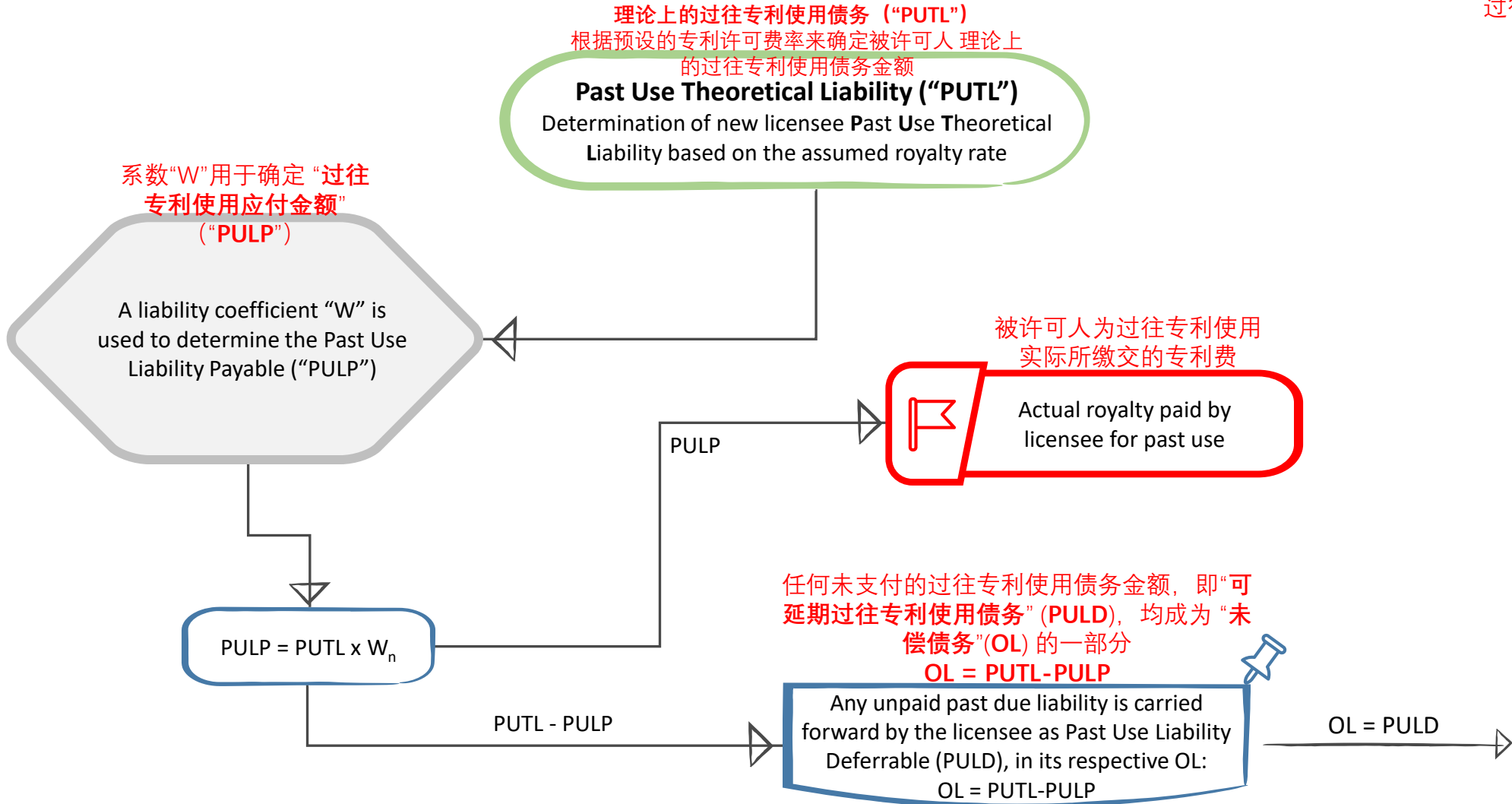
过往专利使用部分



过往专利使用部分

Licensing Incentive Framework for Technologies (“LIFT”): Past Use

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Licensing Incentive Framework for Technologies (“LIFT”): Running

1/10 计量许可

理论上的计量专利使用债务 (“RRTL”)
每个季度基于预设的许可费率来确定

Running Royalty Theoretical Liability (“RRTL”)
based on the assumed royalty rate is determined in each
quarter

Licensing Incentive Framework for Technologies (“LIFT”): Running

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计量许可

系数“W” 每季度确定一次。
W 用于确定“计量专利使用应付金额” (“RRP”) 和“可延期计量专利使用金额” (“RRD”)

理论上的计量专利使用债务 (“RRTL”) 每个季度基于预设的许可费率来确定

A liability coefficient “W” is determined quarterly. W is used to determine both Running Royalty Payable (“RRP”) and Running Royalty Deferrable (“RRD”)

Running Royalty Theoretical Liability (“RRTL”)
based on the assumed royalty rate is determined in each quarter

可许可市场的渗透率

系数“W”

Licensable Market Penetration (“LMP”)	Coefficient W (“W”)
0% ≤ LMP < 5%	10%
5% ≤ LMP < 15%	15%
15% ≤ LMP < 25%	30%
25% ≤ LMP < 35%	45%
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55% ≤ LMP	100%

Licensing Incentive Framework for Technologies (“LIFT”): Running

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计量许可

系数“W” 每季度确定一次。
W 用于确定“计量专利使用应付金额” (“RRP”) 和“可延期计量专利使用金额” (“RRD”)

理论上的计量专利使用债务 (“RRTL”) 每个季度基于预设的许可费率来确定

A liability coefficient “W” is determined quarterly. W is used to determine both Running Royalty Payable (“RRP”) and Running Royalty Deferrable (“RRD”)

Running Royalty Theoretical Liability (“RRTL”) based on the assumed royalty rate is determined in each quarter

最高为25%
Capped at 25%

$$RRP = RRTL \times W$$

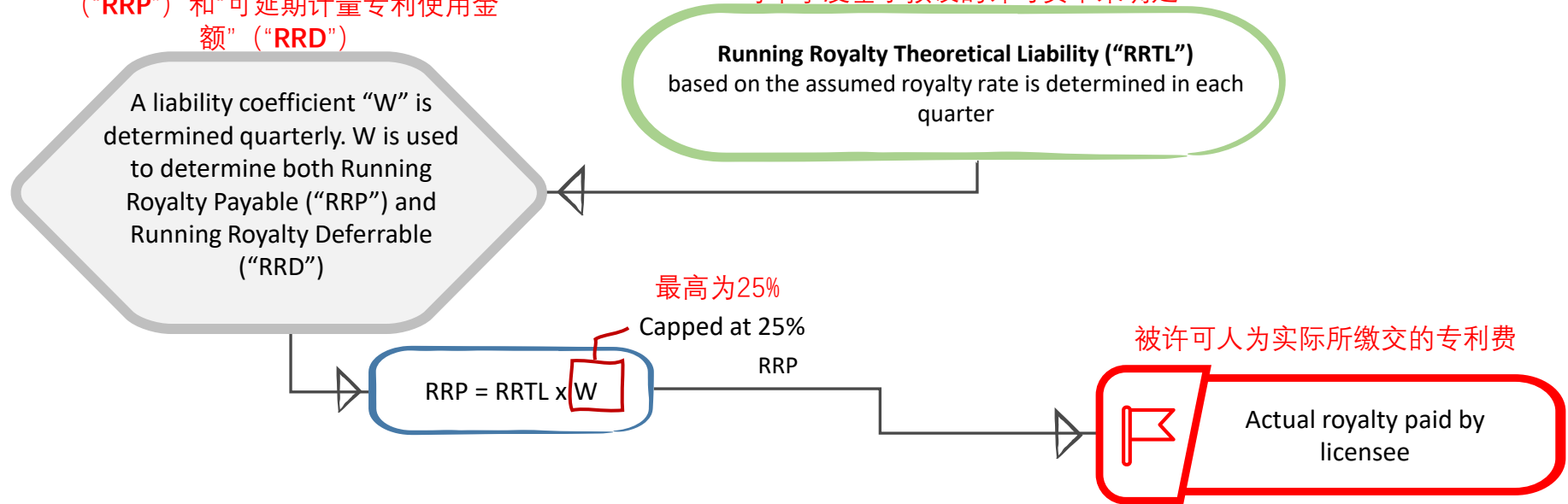
Licensing Incentive Framework for Technologies (“LIFT”): Running

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计量许可

系数“W” 每季度确定一次。
W 用于确定“计量专利使用应付金额” (“RRP”) 和“可延期计量专利使用金额” (“RRD”)

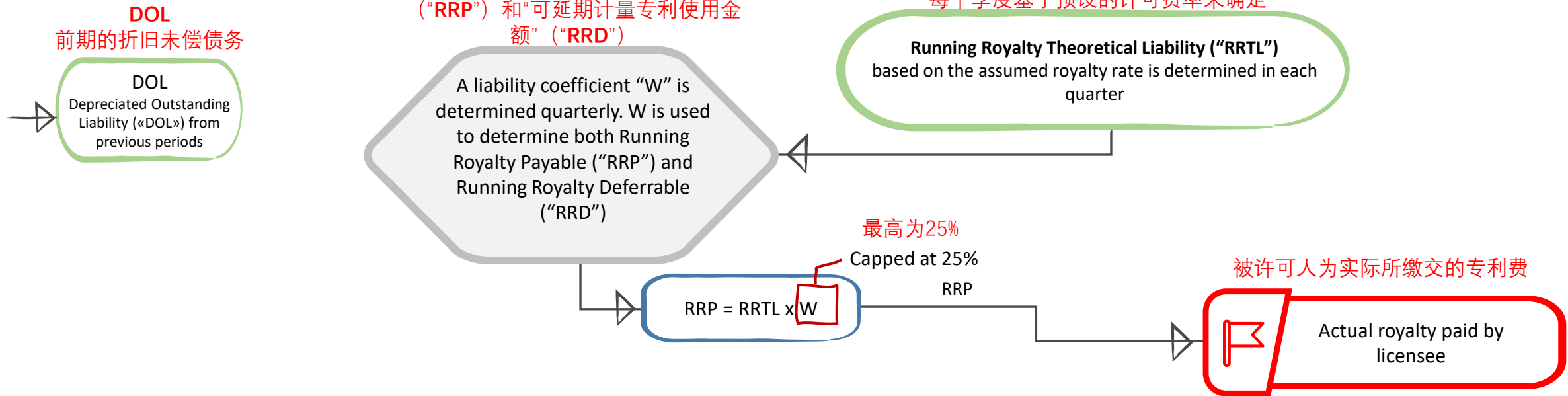
理论上的计量专利使用债务 (“RRTL”) 每个季度基于预设的许可费率来确定



计量许可

Licensing Incentive Framework for Technologies (“LIFT”): Running

5/10 计量许可



Licensing Incentive Framework for Technologies (“LIFT”): Running 6/10

计量许可

系数“W” 每季度确定一次。
W 用于确定“计量专利使用应付金额” (“RRP”) 和“可延期计量专利使用金额” (“RRD”)

理论上的计量专利使用债务 (“RRTL”) 每个季度基于预设的许可费率来确定

Running Royalty Theoretical Liability (“RRTL”)
based on the assumed royalty rate is determined in each quarter

DOL
前期的折旧未偿债务

DOL
Depreciated Outstanding Liability («DOL») from previous periods

A liability coefficient “W” is determined quarterly. W is used to determine both Running Royalty Payable (“RRP”) and Running Royalty Deferrable (“RRD”)

可延期计量专利使用金额 (“RRD”) 的计算方式：
 $RRD = (RRTL - RRP) + DOL$

Calculation of Running Royalty Deferrable (RRD):
 $RRD = (RRTL - RRP) + DOL$

最高为25%
Capped at 25% RRP

$RRP = RRTL \times W$

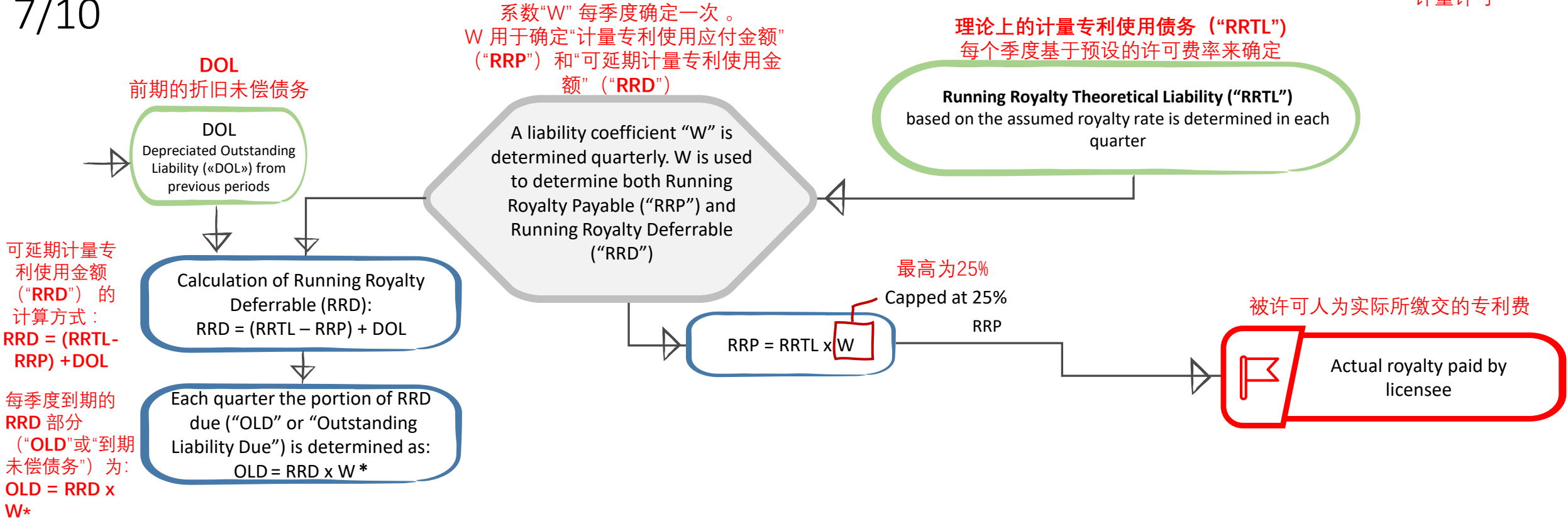
被许可人为实际所缴交的专利费

Actual royalty paid by licensee

Licensing Incentive Framework for Technologies (“LIFT”): Running

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计量许可



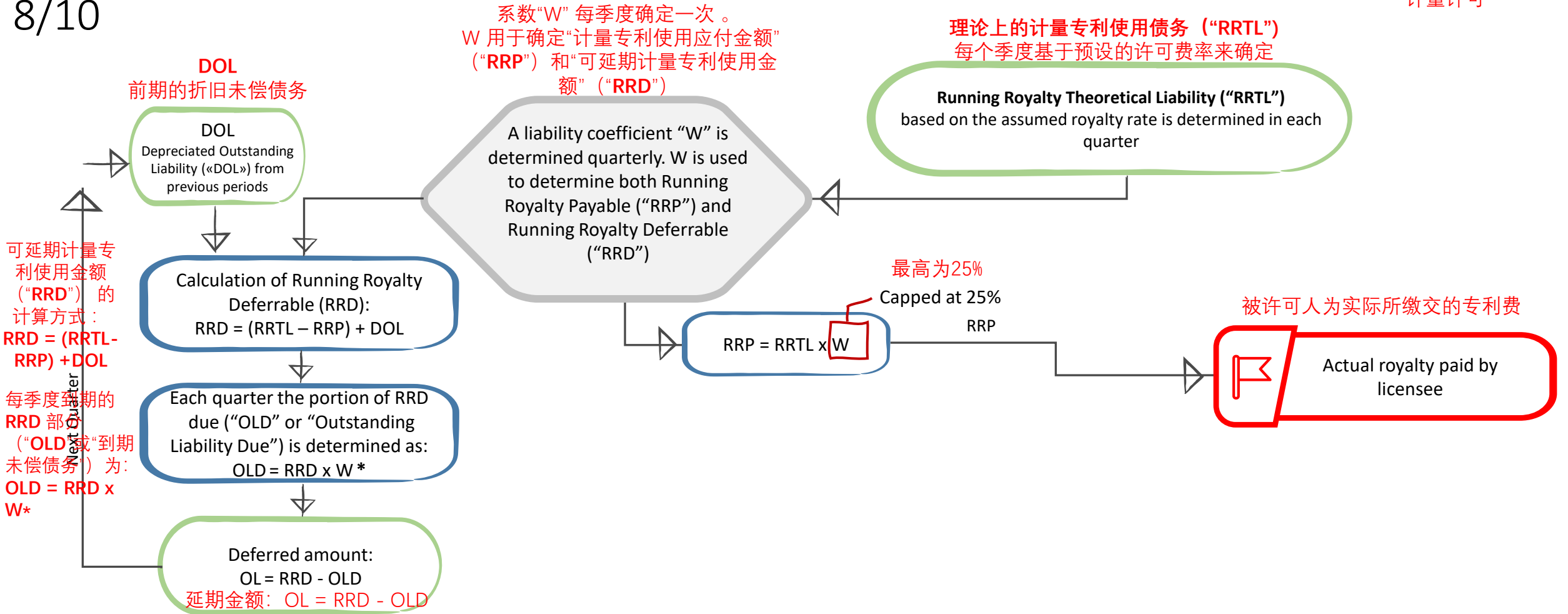
* The difference between RRD and OLD is deferred

* RRD 和 OLD 之间的差异被延期 计量许可

Licensing Incentive Framework for Technologies (“LIFT”): Running

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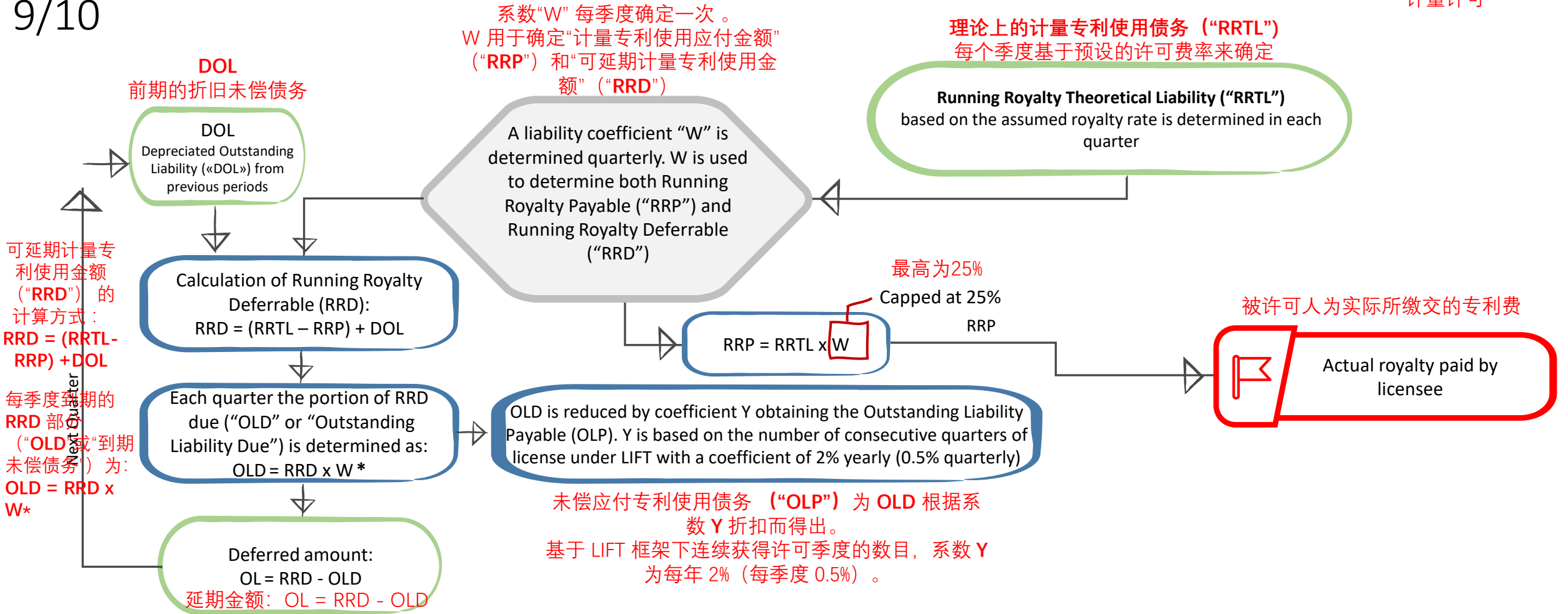


* The difference between RRD and OLD is deferred
* RRD 和 OLD 之间的差异被延期 计量许可
Licensing Incentive Framework for Technologies – LIFT: Running

Licensing Incentive Framework for Technologies (“LIFT”): Running

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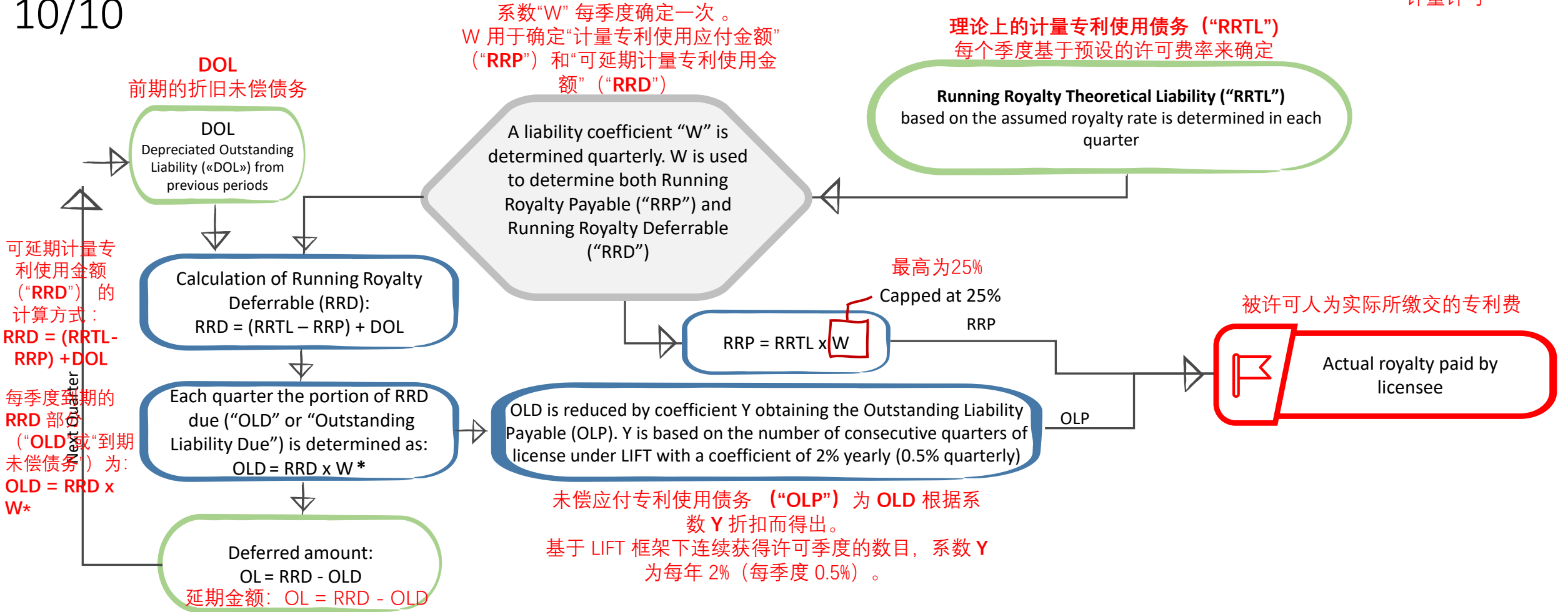
计量许可



* The difference between RRD and OLD is deferred
* RRD 和 OLD 之间的差异被延期 计量许可
Licensing Incentive Framework for Technologies – LIFT: Running

Licensing Incentive Framework for Technologies (“LIFT”): Running

10/10 计量许可



* The difference between RRD and OLD is deferred
* RRD 和 OLD 之间的差异被延期 计量许可
Licensing Incentive Framework for Technologies – LIFT: Running